US00D826185S

(12) **United States Design Patent**
Kosugi et al.

(10) **Patent No.: US D826,185 S**
(45) **Date of Patent: ** Aug. 21, 2018**

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(54) **CEILING HEATER FOR SUBSTRATE PROCESSING APPARATUS**

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(**) Term: **15 Years**

(21) Appl. No.: **29/596,974**

(22) Filed: **Mar. 13, 2017**

(30) **Foreign Application Priority Data**

Oct. 14, 2016 (JP) 022413/2016

(51) **LOC (11) Cl.** **13-03**

(52) **U.S. Cl.**
USPC **D13/182**

(58) **Field of Classification Search**
USPC D13/123–132, 154, 184, 199; D15/138, D15/140, 144.1
CPC H01L 21/67011; H01L 21/67098; H01L 21/67103; H01L 21/67109; H01L 21/67115
See application file for complete search history.

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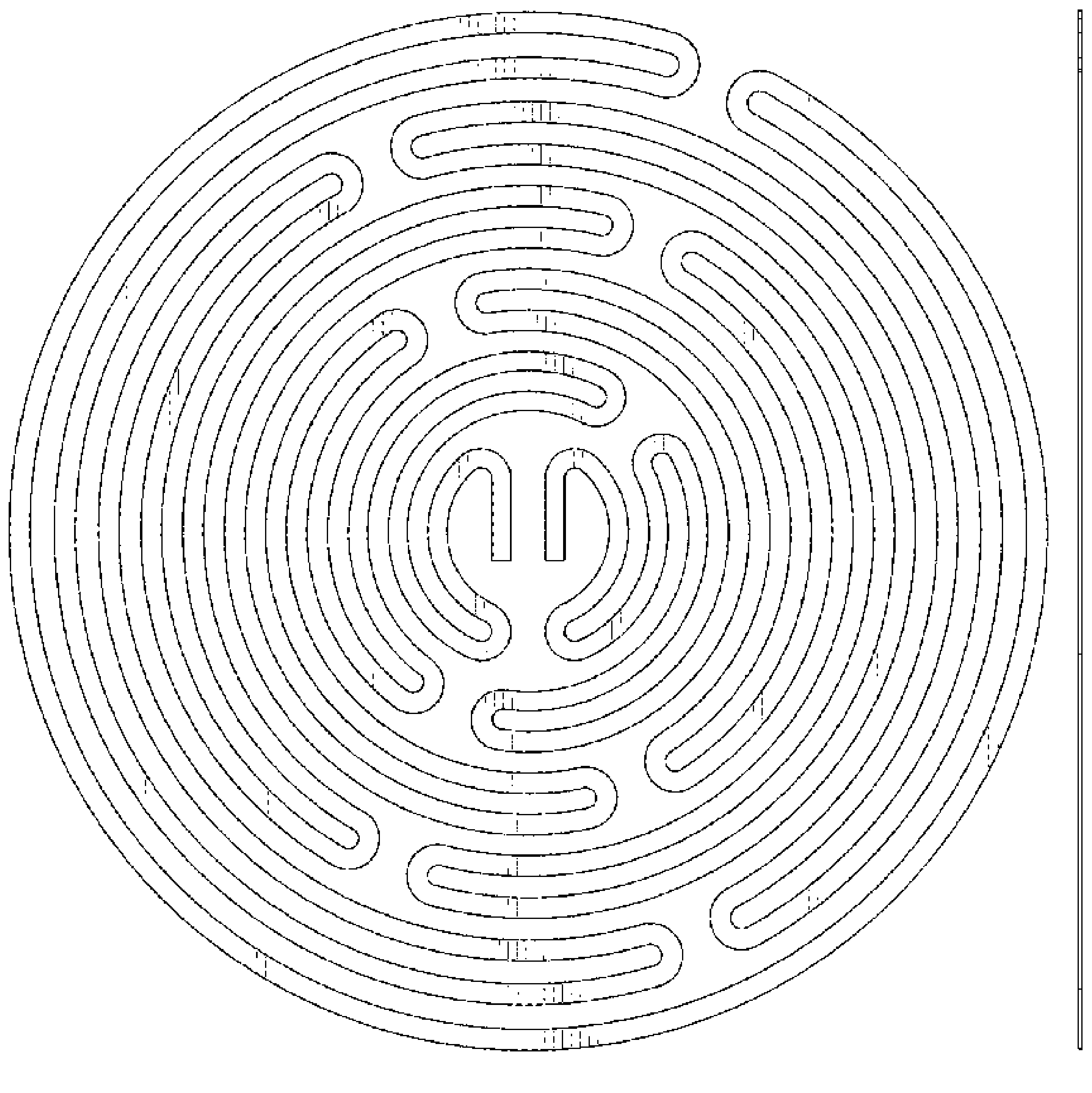
(57) **CLAIM**

We claim the ornamental design for a ceiling heater for substrate processing apparatus, as shown and described.

DESCRIPTION

FIG. **1** is a front, bottom and right side perspective view of a ceiling heater for substrate processing apparartus showing our new design;
FIG. **2** is a front elevational view thereof;
FIG. **3** is a left side elevational view thereof;
FIG. **4** is a right side elevational view thereof;
FIG. **5** is a top plan view thereof;
FIG. **6** is a bottom plan view thereof; and,
FIG. **7** is a rear elevational view thereof.

1 Claim, 4 Drawing Sheets



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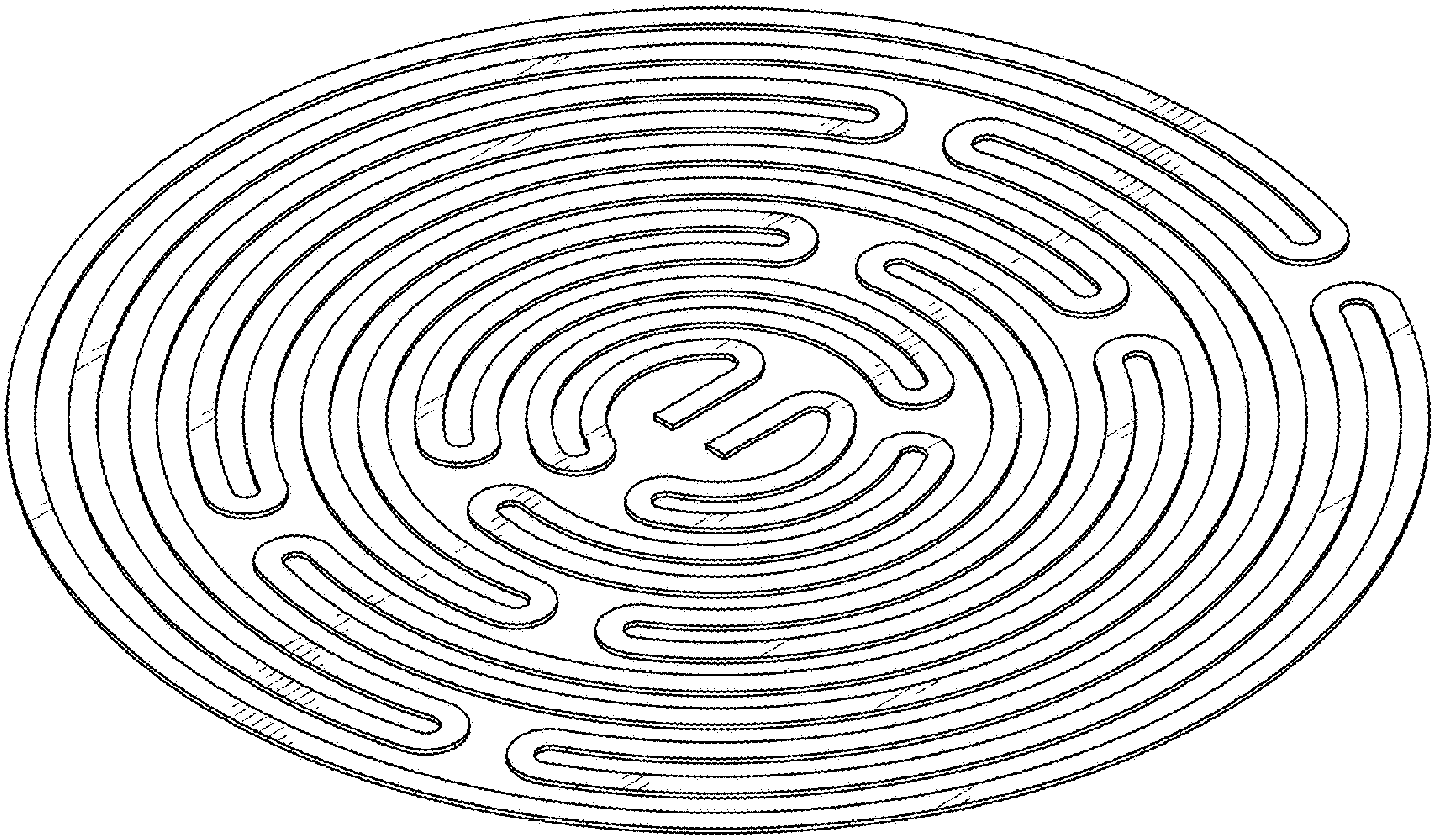

FIG. 1

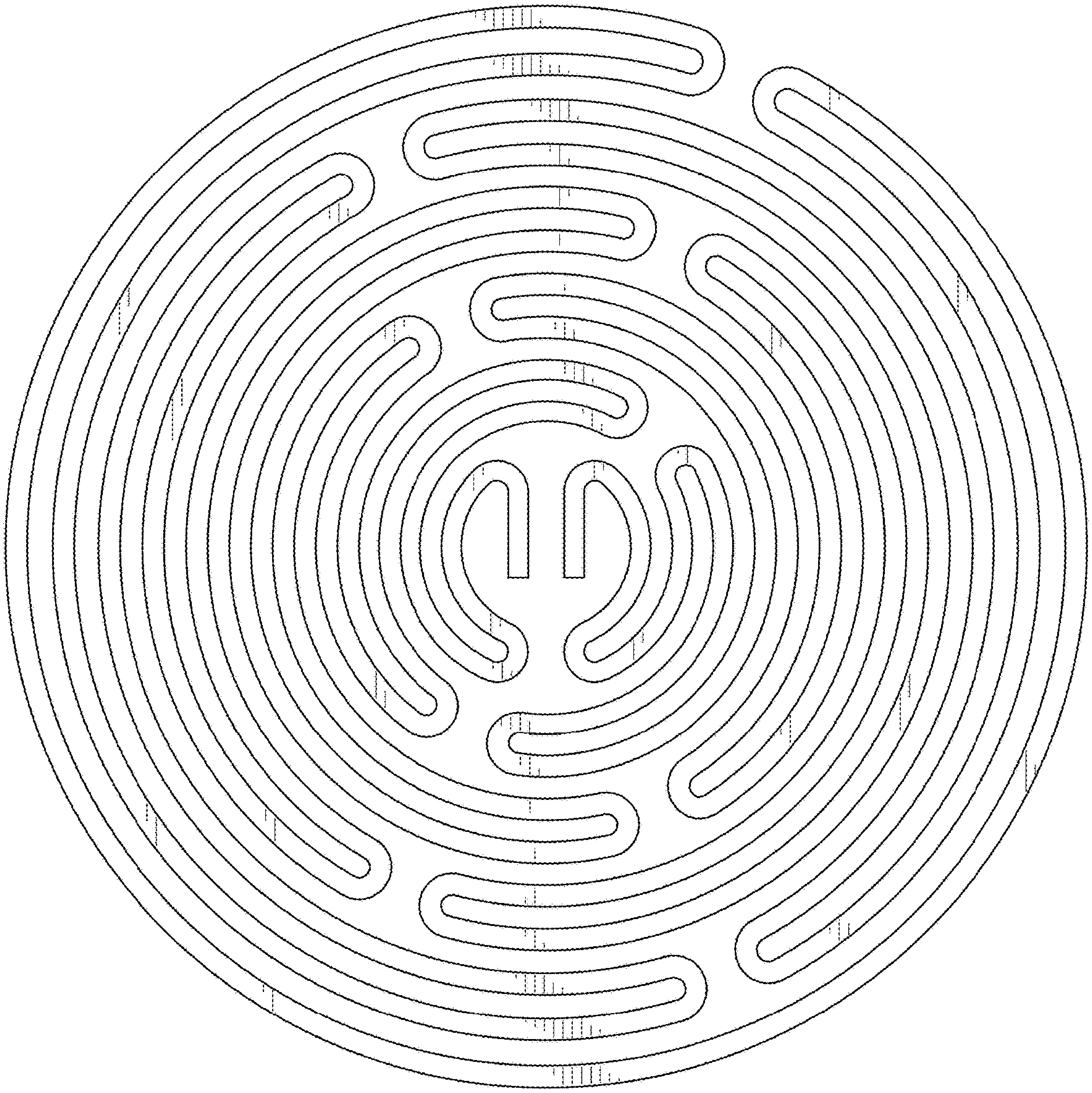

FIG. 2

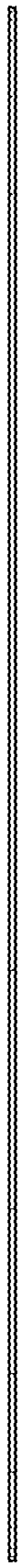

FIG. 3

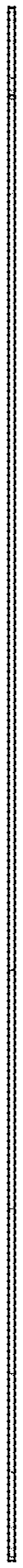

FIG. 4

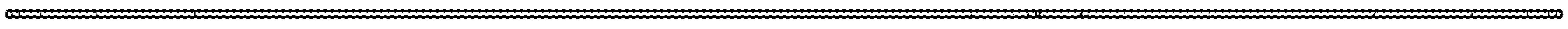

FIG. 5

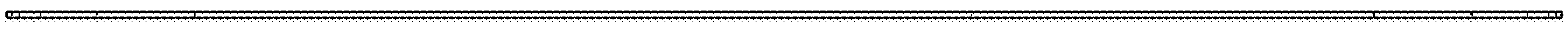

FIG. 6

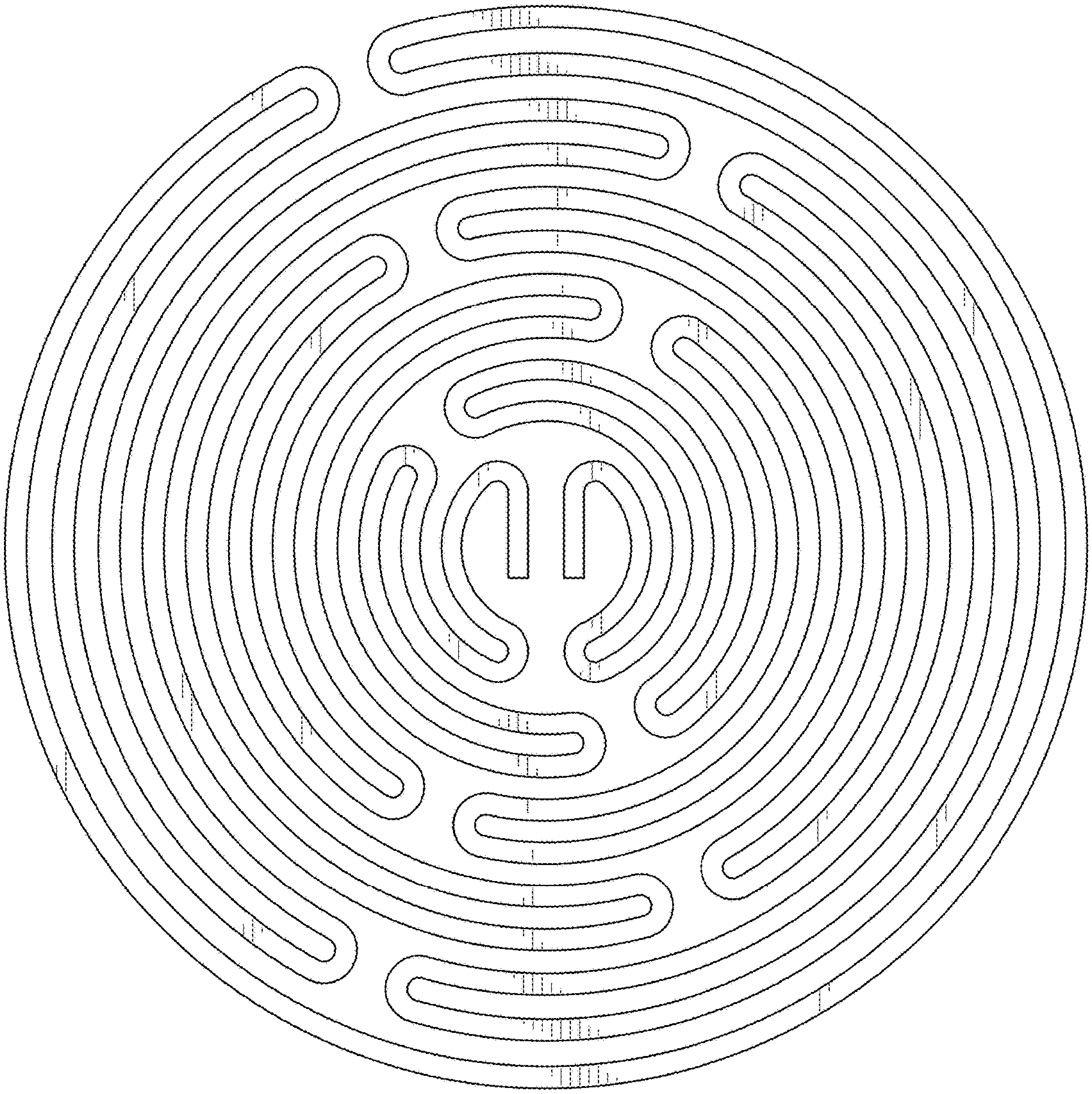

FIG. 7